

Amendments to the Claims

1. **(Currently Amended)** A wafer handling checker comprising:

a plurality of ~~operation~~ training operation wafers each formed of a semiconductor or ceramics to which a conductive film is applied on ~~the~~ a face thereof, or a material having conductive properties;

a cassette having a plurality of slots for housing the plurality of training operation wafers, and a plurality of electrodes for contacting the plurality of training operation wafers when the plurality of training operation wafers are inserted into the plurality of slots;

a vacuum pincette having a conductive suction part for operating ~~each wafer~~ on the plurality of training operation wafers;

voltage application means for applying a voltage between each electrode of the cassette and the conductive suction part of the vacuum pincette; and

state detection means for detecting contact between the vacuum pincette and each training operation wafer by detecting a potential of each electrode of the cassette or a current flowing to ~~the~~ an electrode.

2. **(Currently Amended)** The wafer handling checker according to Claim 1, wherein the cassette has display means for specifying a training operation wafer to be operated on based on operation specification information.

3. **(Currently Amended)** The wafer handling checker according to Claim 2, further comprising decision means for deciding ~~the presence or absence of~~ whether an erroneous operation occurs based on a result of detection by the state detection means and the operation specification information.

4. **(Currently Amended)** The wafer handling checker according to Claim 3, wherein the decision means has output means for generating sound when ~~it~~ the decision means decides ~~the presence of erroneous operation~~ has occurred.